IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| In re Patent Application of: |) | Group Art Unit: 2822 |
|--------------------------------|---|------------------------------|
| Koichiro TANAKA et al. |) | Examiner: Mary A. Wilczewski |
| Serial No. 10/749,505 |) | |
| Filed: January 2, 2004 |) | |
| For: LASER IRRADIATION METHOD, |) | RECEIVED |
| METHOD FOR MANUFACTURING |) | OCT 3 1 2007 |
| SEMICONDUCTOR DEVICE, AND |) | |
| LASER IRRADIATION SYSTEM |) | OFFICE OF PETITIONS |

PETITION TO WITHDRAW FROM ISSUE

Honorable Commissioner of Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Applicant hereby petitions that the subject application be withdrawn from issue to permit consideration of an Information Disclosure Statement under 37 CFR 1.97 (submitted herewith) and a Request for Continued Examination (RCE) (also submitted herewith).

Also submitted herewith is the requisite fee of \$130.00 set forth in 37 CFR 1.17(i).

In view of the foregoing, it is urged that this petition is in order and, accordingly, a prompt grant thereof is requested.

The Commissioner is hereby authorized to charge any fees which may be further required in this application, except the issue fee, or credit any overpayment to Deposit

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Account No. 50-2280, under the above order number. A <u>duplicate</u> of this sheet is attached.

Respectfully submitted,

Eric J. Robinson

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U.S. SERIAL NO. 10/749,505 FILED: JANUARY 2, 2004

FOR: LASER IRRADIATION METHOD, METHOD FOR MANUFACTURING

SEMICONDUCTOR DEVICE, AND LASER IRRADIATION SYSTEM

KOICHIRO TANAKA ET AL. DOCKET NO.: 0756-7244

SPECIAL PROCEDURES SUBMISSION

PETITION TO WITHDRAW FROM ISSUE

DELIVER TO:

Office of Petitions U.S.P.T.O.

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OFFICE OF PETITIONS

PLEASE FAX COPY OF DECISION ON PETITION TO 571-434-9499